

## **Electrostatically Focused Addressable Field Emission Array Chips for High-Speed Massively Parallel Maskless Digital e-Beam Direct Write Lithography and Scanning Electron Microscopy**

### **Disclosure Number**

199900665

### **Technology Summary**

A method for massively parallel electron-beam lithography of semiconductor wafers, and also for massively Parallel Scanning Electron Microscopy.

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